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geologia de engenharia livro full pdf geologia de engenharia livro full video geologia de engenharia livro full...Evaluation of the effects of chronic carbon tetrachloride administration on oxidative status in the rat. In order to evaluate the effects of chronic administration of carbon tetrachloride (CCl<sub>4</sub>) on lipid peroxidation and some antioxidant enzyme activities in the liver of rats, 24 rats were divided into six groups. Animals in groups I, II, III and IV received intraperitoneally (i.p.) 0.5, 1.0, 1.5 or 2.0 ml kg<sup>-1</sup> b.w. of pure CCl<sub>4</sub> at a dose of 0.3 ml kg<sup>-1</sup> b.w. Once per week, animals in group III and IV received the same amount of olive oil as a vehicle, whereas the animals in groups I and II were used as sham-treated controls. After the treatment period of 3 months, biochemical analysis of blood was performed as well as the assessment of glutathione-S-transferase (GST) and peroxidase (POD) activities in the liver. In addition, thiobarbituric acid-reactive substances (TBARS), reduced glutathione (GSH), total thiols (SH), non-protein sulfhydryl groups (NP-SH) and superoxide dismutase (SOD) activity were determined in the liver. In the animals treated with CCl<sub>4</sub>, significant increases of GST activity, TBARS and GSH were observed in the liver. A significant increase of POD activity was also detected. Our findings confirm that CCl<sub>4</sub> induces oxidative stress and indicates the involvement of lipid peroxidation in the mechanism of CCl<sub>4</sub> toxicity in rats.

1. Technical Field The present invention is directed to the field of semiconductor processing; more specifically, to the field of plasma etching of semiconductor substrates.

2. Description of the Related Art Plasma etching is a common technique for removing materials from a semiconductor substrate. However, many materials which are attacked by a conventional plasma etch are often also attacked during a conventional cleaning process. Some of these materials include: aluminum, copper, tungsten, polysilicon, and cobalt. When the etch and cleaning processes are performed in a single etch reactor, a conventional cleaning process typically

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